The Materials Preparation and Measurement Laboratory (MPML) provides shared research facilities for sample fabrication, processing, patterning and characterization. Instrumentation encompasses scanning probe microscopes (AFM and STM), scanning electron microscopes (SEM), optical microscopes, optical lithography and imaging, sample cutting-polishing, surface coating, thermal characterization, optical characterization via steady-state and time-resolved fluorescence, absorbance, reflectance, Raman, and light scattering.

A key aspect of the Lab is extensive one-on-one training with experienced PhD-level staff. After training, it is possible for all users, from undergrads, graduate students, and postdocs to external users of all levels, to operate instruments by themselves. Qualified users are given 24/7 access to the instruments. MPML staff may also provide direct service on an as-needed basis.

The MPML is open to all interested academic and industrial users.

A new rate policy is in effect as of October 1st, 2016. Please see our Access and Rates page.

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